3rd Announcement

The 27th Symposium on Photomask and Next Generation Lithography Mask Technology

Photomask Japan 2021 Digital Forum

April 20 (Tue.) - 21 (Wed.), 2021

Symposium Chair: Prof. Takeo Watanabe, University of Hyogo (Japan)
Organized by Photomask Japan and SPIE, Co-organized by BACUS and EMLC

Considering the ongoing situation of COVID-19, we have concluded we will not be able to take sufficient safety measures at an in-person symposium. Photomask Japan 2021 will be held fully online on April 20-21. We appreciate your understanding.



You can also enjoy PMJ movies and Sakura Drone Movie!



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For more information, contact: Photomask Japan Secretariat c/o JTB Communication Design, Inc. Celestine Shiba Mitsui Bldg., 3-23-1 Shiba, Minato-ku, Tokyo 105-8335, Japan E-mail: pmj@jtbcom.co.jp http://www.photomask-japan.org

Program

Latest Program https://www.photomask-japan.org/program.html

Keynote Speaker: Dr. Klaus Schuegraf (Intel Corporation) The program is subject to change without notice.

April 20 (Tue.)			April 21 (Wed.)		
PDT UTC-7	CEST UTC+2	JST UTC+9 Digital Forum	PDT UTC-7	CEST UTC+2	JST UTC+9 Digital Forum
19-Apr	20-Apr	8:00 - 8:10 Opening	20-Apr	21-Apr	
16:00 17:30	1:00 2:30	8:10 - 9:30 Session 1 Opening Session: Day 1	16:00 17:40	1:00 2:40	8:00 - 9:40 Session 7 Opening Session: Day 2
		9:30 - 9:50 Break	17:40	2:40	9:40 - 10:00 Break
17:50 18:50	2:50 3:50	9:50 - 10:50 Session 2 ML & MPC	18:00	3:00	9.40 - 10.00 Break
		10:50 - 11:10 Break	ı	ı	10:00-12:20 Session 8
19:10 20:20	4:10 5:20	11:10 - 12:20 Session 3 EUV from Asia 1	20:20	5:20	NIL
		12:20 - 13:50 Lunch Break			12:20 - 13:50 Lunch Break
21:50 22:30	6:50 7:30	13:50 - 14:30 Session 4 Lithography	21:50 23:00	6:50 8:00	13:50 - 15:00 Session 9 EUV from Asia 2
		14:30 - 14:50 Break	20.00	0.00	15:00 - 15:20 Break
22:50 23:50	7:50 l 8:50	14:50 - 15:50 Session 5 PSM, Etching & FPD	23:20	8:20	15:20 - 16:50 Session 10
20-Apr		15:50 - 16:10 Break	21-Apr 0:50	9:50	Inspection
0:10 2:00	9:10 11:00	16:10 - 18:00 Session 6 EUV from Europe			16:50 - 17:10 Break
Poster presentations will be available from April 20th (JST).			1:10 	10:10 	17:10 - 18:50 Session 11 Writing & CD Analysis
			3:00	12:00	18:50 - 19:00 Closing

PMJ movies and Sakura movie will be provided during break time.

For registration details, please see https://www.photomask-japan.org/registration.html

Technical Exhibition (Online)

• April 20 (Tue.) 9:00- 18:00

• April 21 (Wed.) 9:00- 18:00